

THIN FILM CMOS CALIBRATION STANDARD
HAVING PROTECTIVE COVER LAYER

ABSTRACT OF THE DISCLOSURE

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Embodiments of the invention include a calibration standard for semiconductor metrology tools. The standard comprises a substrate having a surface with a calibration layer formed thereon. A protective layer is formed over the underlying calibration layer. The calibration layer and protective layer are each
10 formed to precise tolerances. The invention also includes methods for forming a calibration standard for semiconductor metrology tools.